

Resource Summary Report

Generated by [NIF](#) on Sep 3, 2026

Texas State University PEALD System

RRID:SCR_028201

Type: Tool

Proper Citation

Texas State University PEALD System (RRID:SCR_028201)

Resource Information

URL: <https://sro.txst.edu/sro-facilities/sro-nrsc/sro-nrsc-peald.html>

Proper Citation: Texas State University PEALD System (RRID:SCR_028201)

Description: Facility plasma-enhanced atomic layer deposition (PEALD) system from Arradance utilizes high-speed pulse valves to sequentially deliver reactants that combine to deposit thin films on the surface of a sample at temperatures up to 300C. Eight precursor positions (4 metalorganic + 4 oxidizer) and three plasma gases (N2, O2, H2) enable a wide range of films and process optimization. Plasma-enhanced atomic layer deposition system used for conformal, atomic-scale thin film growth with excellent uniformity and thickness control.

Synonyms: PEALD System (FlexAL-PEALD)

Resource Type: instrument resource

Keywords: PEALD, atomic layer deposition, thin films, plasma deposition, conformal coating,

Availability: Restricted

Resource Name: Texas State University PEALD System

Resource ID: SCR_028201

Alternate URLs: <https://sro.txst.edu/sro-facilities/sro-nrsc.html>,
<https://www.sharedinstrumentation.ucsb.edu/instruments/nanotech-nanofabrication-facility/multi-wafer-evaporator>

Record Creation Time: 20260327T054534+0000

Record Last Update: 20260829T183543+0000

Ratings and Alerts

No rating or validation information has been found for Texas State University PEALD System.

No alerts have been found for Texas State University PEALD System.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.